

## Supplementary Information

### **Synergistic boosting electrical output of moisture-electric generator based on CCNF-LiCl-PAM hydrogel**

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**Fig. S1.** Schematic illustration of preparation process of the CLP hydrogel.

**Fig. S2.** Conductivities of the CLP hydrogels with different LiCl concentrations.

**Fig. S3.** XRD patterns of CCNF-PAM and CCNF-LiCl-PAM (CLP) Hydrogels.

**Fig. S4.** EDS mapping of C, N, O, Li and Cl elements in the CLP hydrogel.

**Fig. S5.** (a) Conductivity of the CLP hydrogel and (b) electrical outputs of the CLP-MEG based on the CLP hydrogel prepared by different BIS contents.

**Fig. S6.** Surface potentials of MEGs with different salts were simulated using COMSOL software.

**Fig. S7.** Output voltages of the CLP-MEGs with different areas.

**Fig. S8.** CV curves of the CLP-MEG with different top electrodes (Zn, Al, Ag, and Cu).

**Fig. S9.** TG and DTG curves of the pristine CLP hydrogel and the CLP hydrogel after 90 days.

**Fig. S10.** SEM images of the pristine Zn electrode (a-c) and the Zn electrode after 90 days (d-f).

**Fig. S11.** XRD patterns of the pristine Zn electrode and the Zn electrode after 90 days.

**Fig. S12.** XPS spectra of the Zn electrode before and after 90 days.

**Fig. S13.** EDS mapping of Zn element on top and bottom surfaces of the CLP hydrogel after 90 days.

**Fig. S14.** EDS mapping of Zn and Li elements on the LIG electrode after 90 days.

**Fig. S15.** Schematic illustration of fabrication process of the parallel-integrated MEGs.

**Fig. S16.** Schematic illustration of fabrication process of the series-integrated MEGs.

**Fig. S17.** Voltage output of 90 MEG units connected in parallel.

**Fig. S18.** Current output of 60 MEG units connected in series.

**Fig. S19.** Voltage curve of a 10  $\mu$ F commercial capacitor charged directly by 60 MEG units connected in series. The inset shows the corresponding circuit diagram.

**Fig. S20.** Output voltage (a) and current (b) of 12 MEG units connected in parallel.

**Fig. S21.** Photography of four hygro-thermographs in parallel directly powered by a single large-area CLP-MEG ( $5 \times 5$  cm<sup>2</sup>).

**Table S1.** EDS elemental composition on top surface of the CLP hydrogel after 90 days.

**Table S2.** EDS elemental composition on bottom surface of the CLP hydrogel after 90 days.

**Movie S1.** A calculator powered by a MEG unit.

**Movie S2.** A hygro-thermograph powered by a MEG unit.

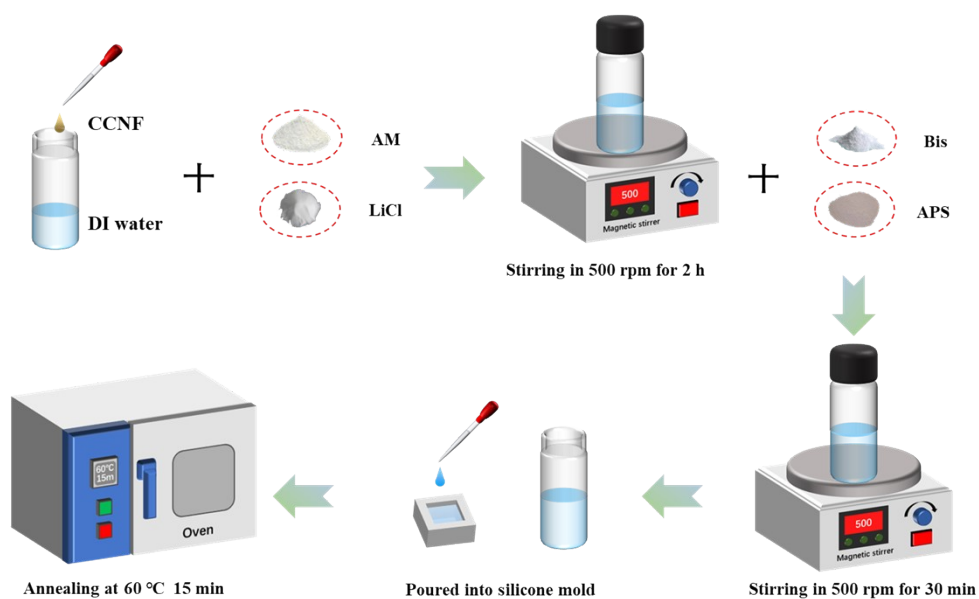
**Movie S3.**  $3 \times 1.0$  W LED lamps powered by 60 MEG units connected in series.

**Movie S4.** Twelve hygro-thermographs in parallel powered by 12 MEG units connected in parallel.

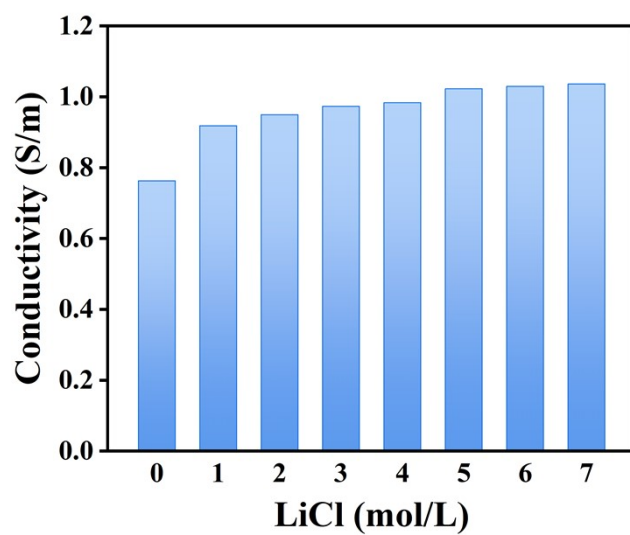
**Movie S5.** One smartphone directly powered by a 1.0 F capacitor that is charged by the integrated  $3 \times 3$  MEGs.

**Movie S6.** An LED screen directly powered by a 1.0 F capacitor that is charged by the integrated  $3 \times 3$  MEGs.

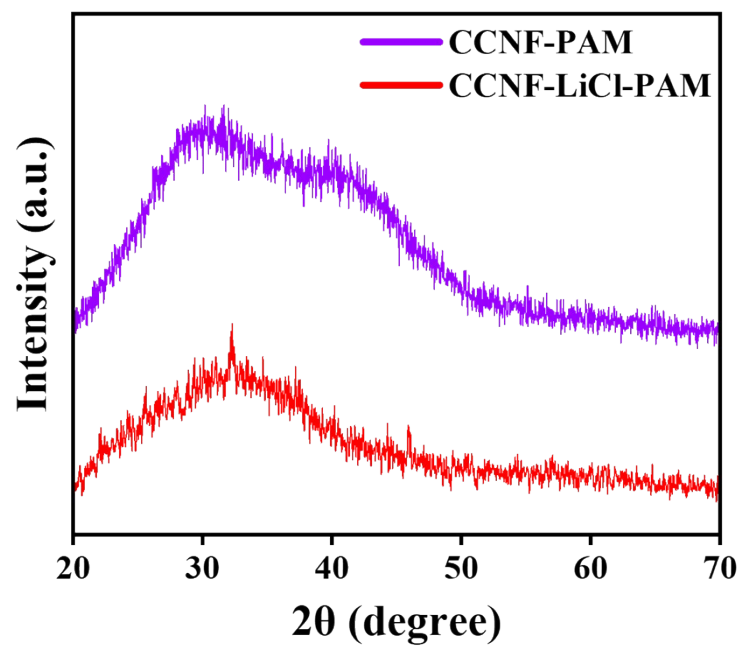
**Movie S7.** Four hygro-thermographs in parallel directly powered by a single  $5 \times 5$  cm<sup>2</sup> CLP-MEG.



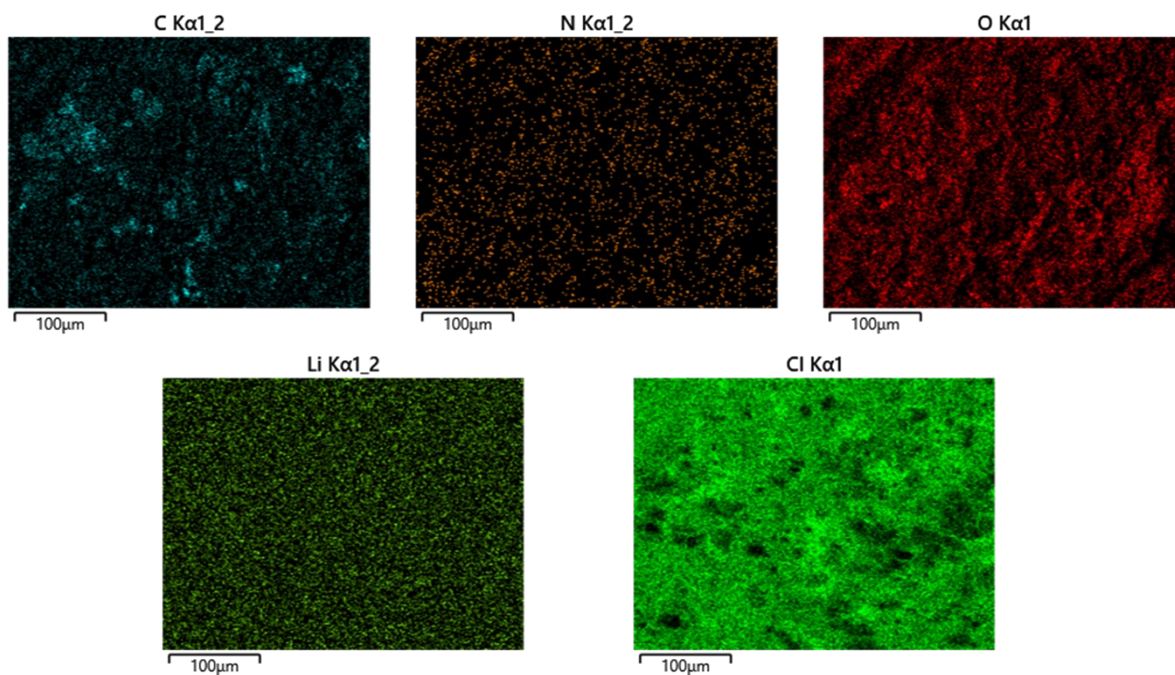
**Fig. S1.** Schematic illustration of preparation process of the CLP hydrogel.



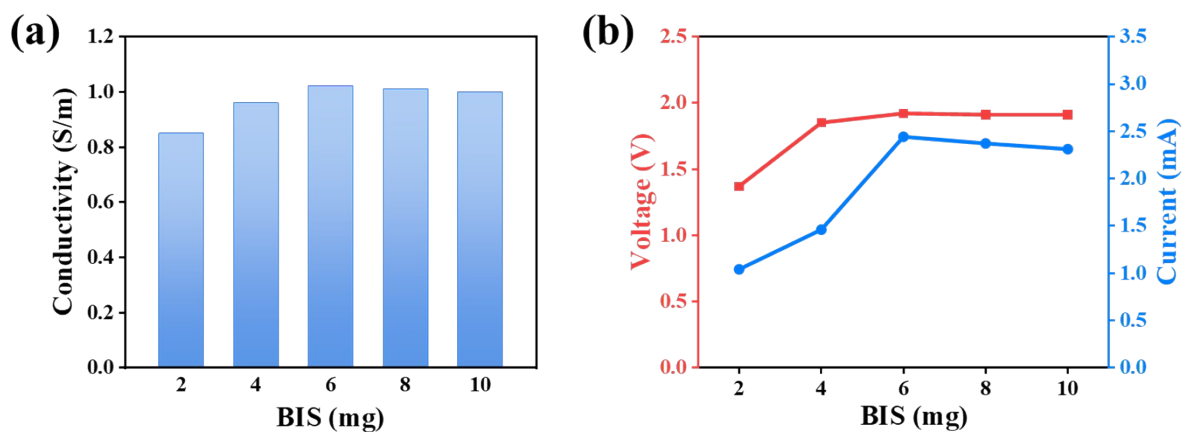
**Fig. S2.** Conductivities of the CLP hydrogels with different LiCl concentrations.



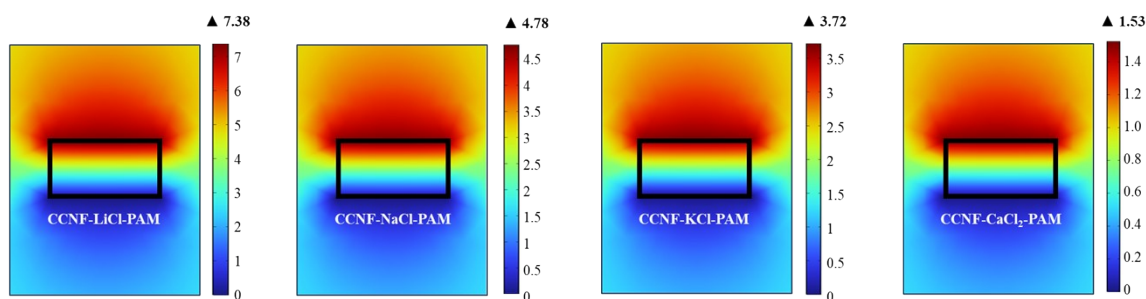
**Fig. S3.** XRD patterns of CCNF-PAM and CCNF-LiCl-PAM (CLP) Hydrogels.



**Fig. S4.** EDS mapping of C, N, O, Li and Cl elements in the CLP hydrogel.



**Fig. S5.** (a) Conductivity of the CLP hydrogel and (b) electrical outputs of the CLP-MEG based on the CLP hydrogel prepared by different BIS contents.



**Fig. S6.** Surface potentials of MEGs with different salts were simulated using COMSOL software. The highest and lowest surface potential belongs to the MEGs with monovalent Li<sup>+</sup> and divalent Ca<sup>2+</sup> ions, respectively. Under the same conditions, the greater difference in surface potential of the nanochannels, the faster the ions migration within the channels.

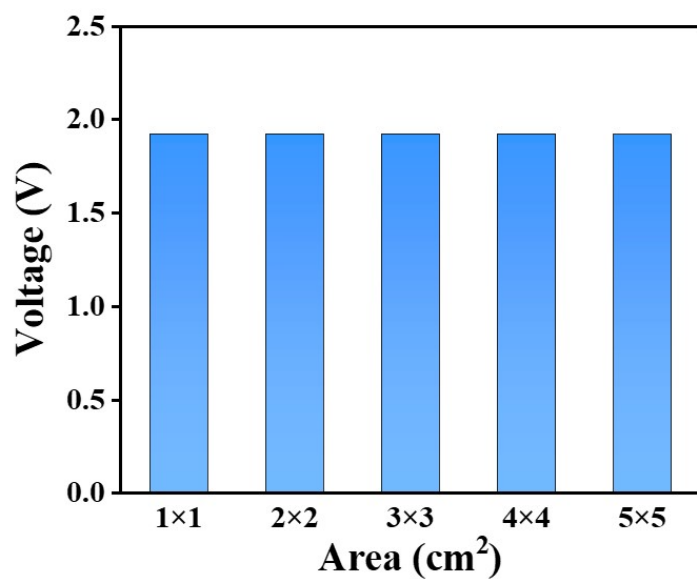


Fig. S7. Output voltages of the CLP-MEGs with different areas.

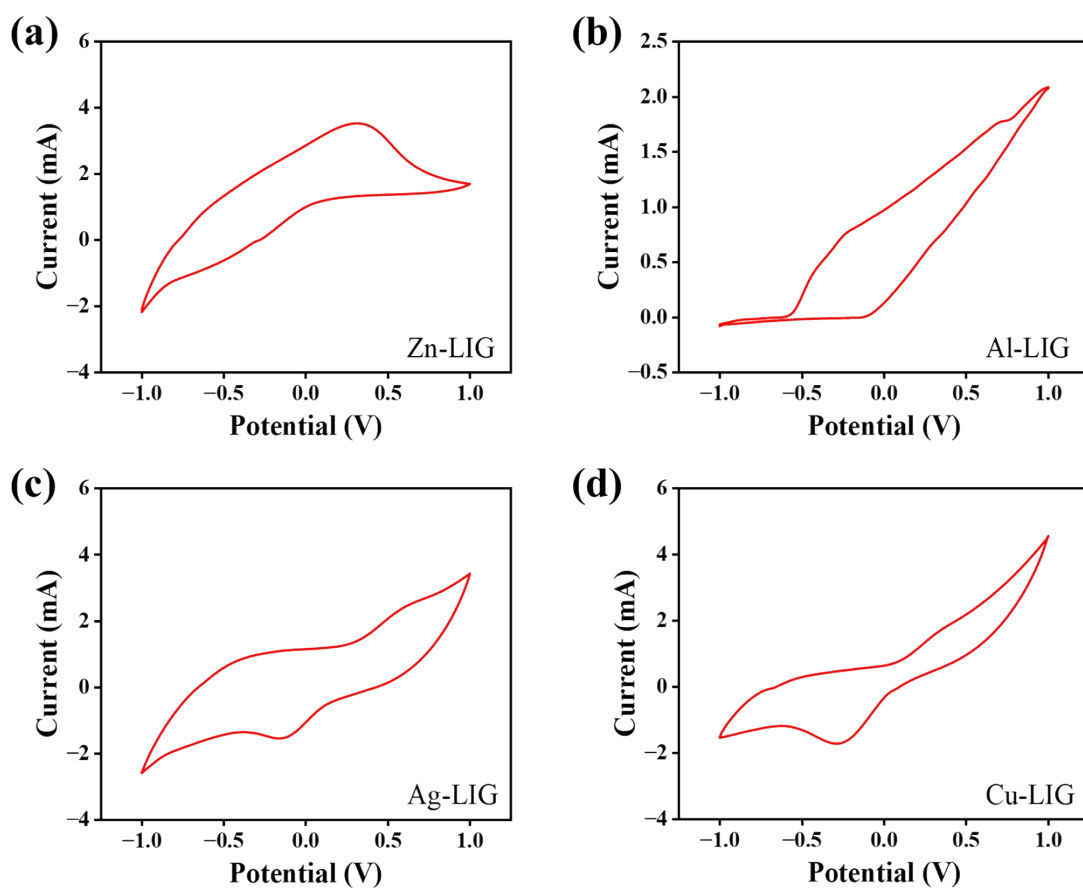
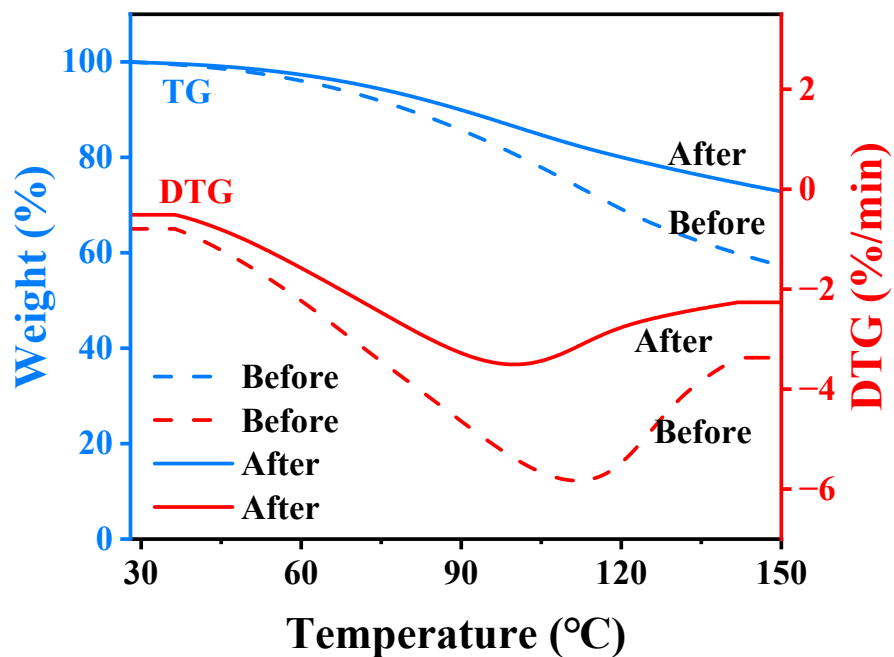
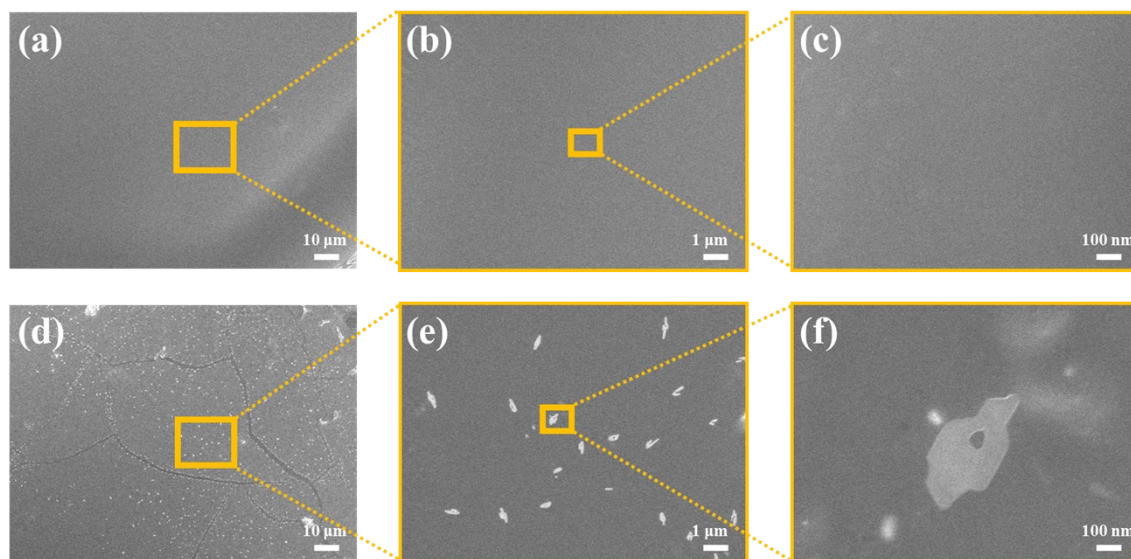


Fig. S8. CV curves of the CLP-MEG with different top electrodes (Zn, Al, Ag, and Cu).



**Fig. S9.** TG and DTG curves of the pristine CLP hydrogel and the CLP hydrogel after 90 days.



**Fig. S10.** SEM images of the pristine Zn electrode (a-c) and the Zn electrode after 90 days (d-f).

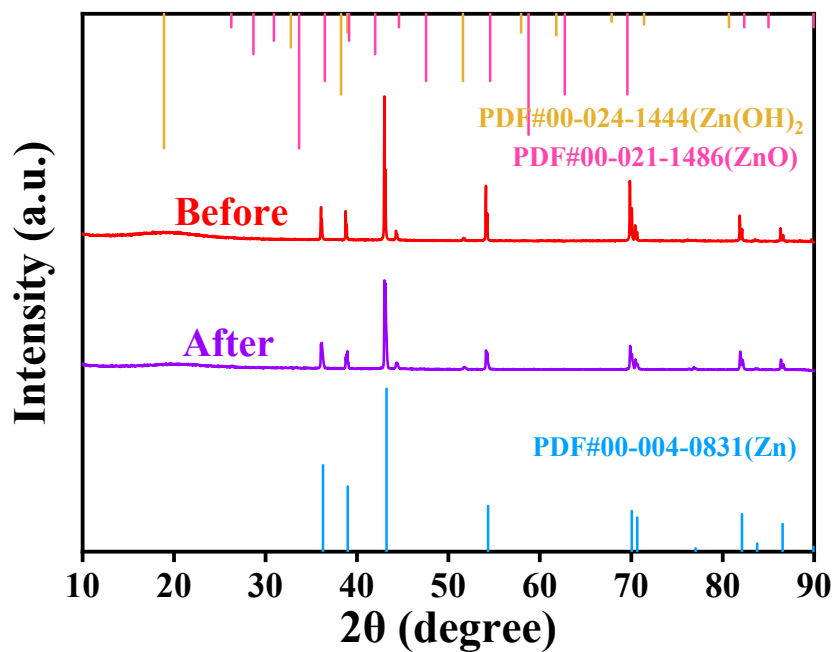


Fig. S11. XRD patterns of the pristine Zn electrode and the Zn electrode after 90 days.

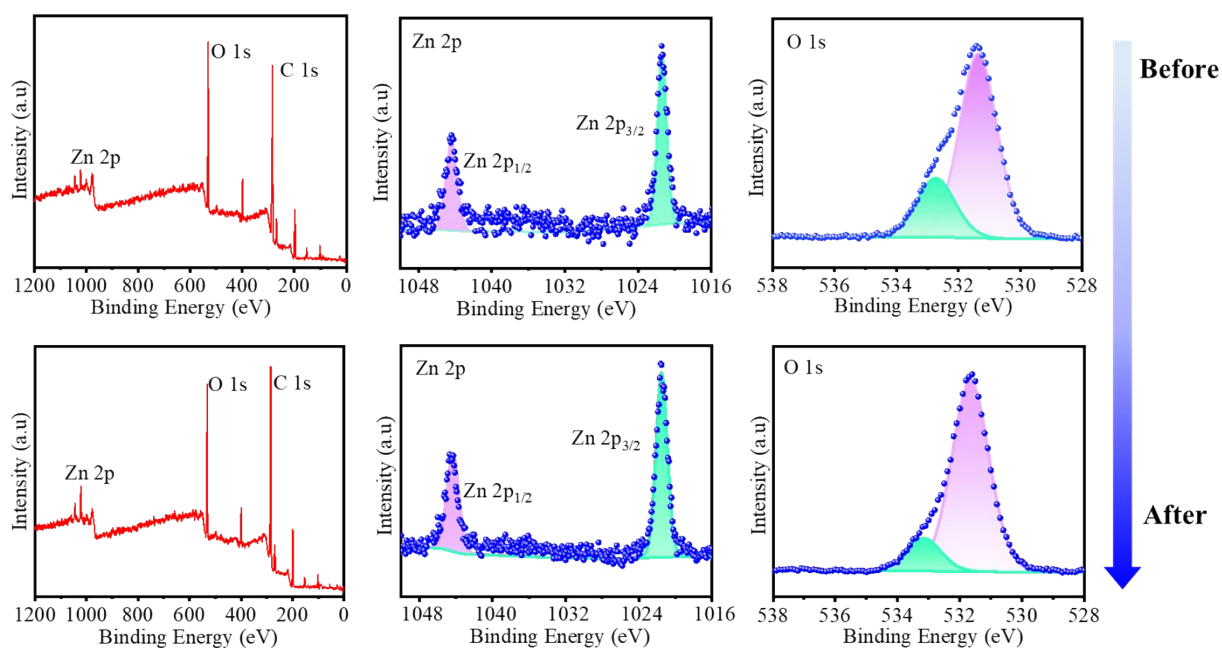
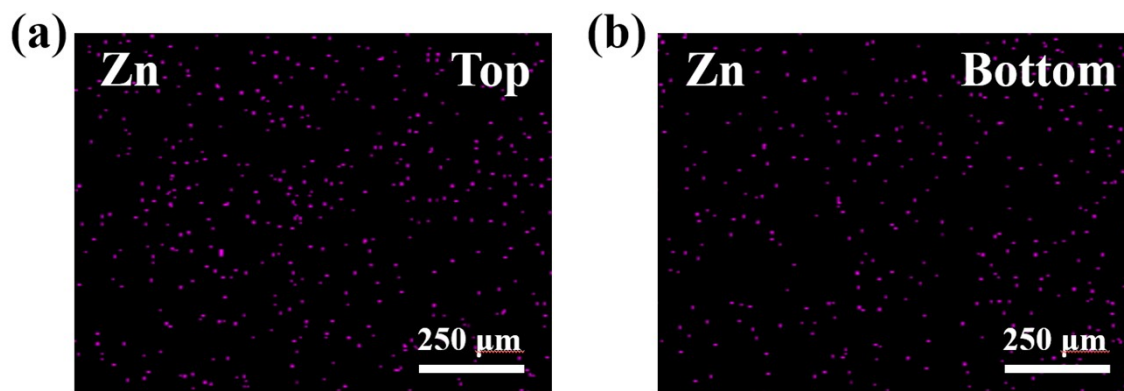
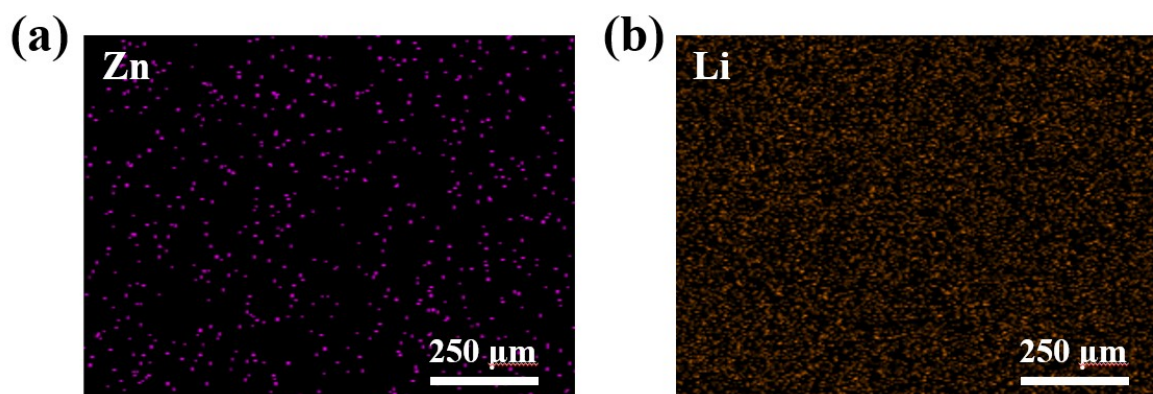


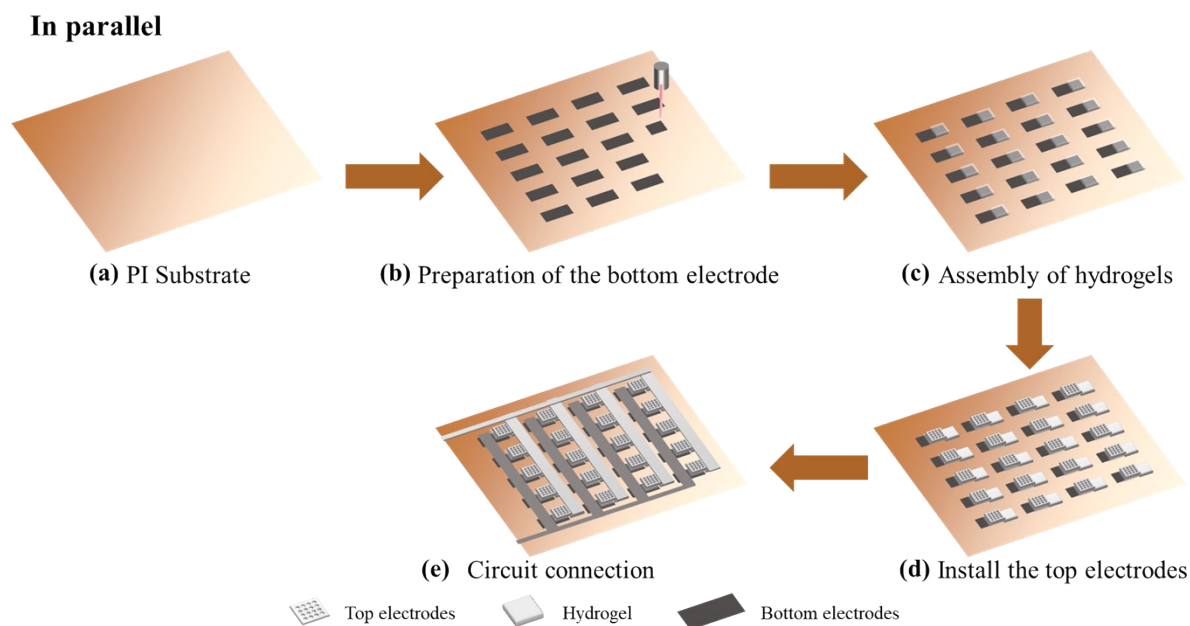
Fig. S12. XPS spectra of the Zn electrode before and after 90 days.



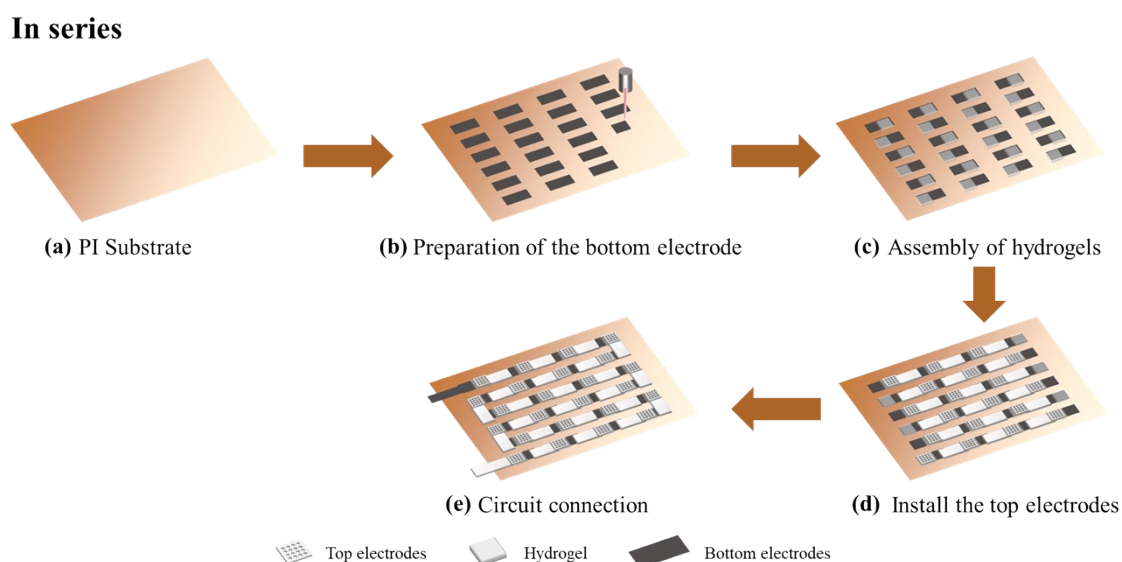
**Fig. S13.** EDS mapping of Zn element on top and bottom surfaces of the CLP hydrogel after 90 days.



**Fig. S14.** EDS mapping of Zn and Li elements on the LIG electrode after 90 days.



**Fig. S15.** Schematic illustration of fabrication process of the parallel-integrated MEGs. (a) PI substrate. (b) Fabrication of LIG electrodes on the PI substrate using a programmable laser engraving machine. (c) Assembly of the prepared hydrogel onto the bottom LIG electrode. (d) Assembly of top porous-Zn electrodes on the hydrogel surface. (e) The parallel-integrated MEGs are fabricated via end-to-end and head-to-head connections.



**Fig. S16.** Schematic illustration of fabrication process of the series-integrated MEGs. (a) PI substrate. (b) Fabrication of LIG electrodes on the PI substrate using a programmable laser engraving machine. (c) Assembly of the prepared hydrogel onto the bottom LIG electrode. (d) Assembly of top porous-Zn electrodes on the hydrogel surface. (e) The series-integrated MEGs are fabricated via head-to-end connections.

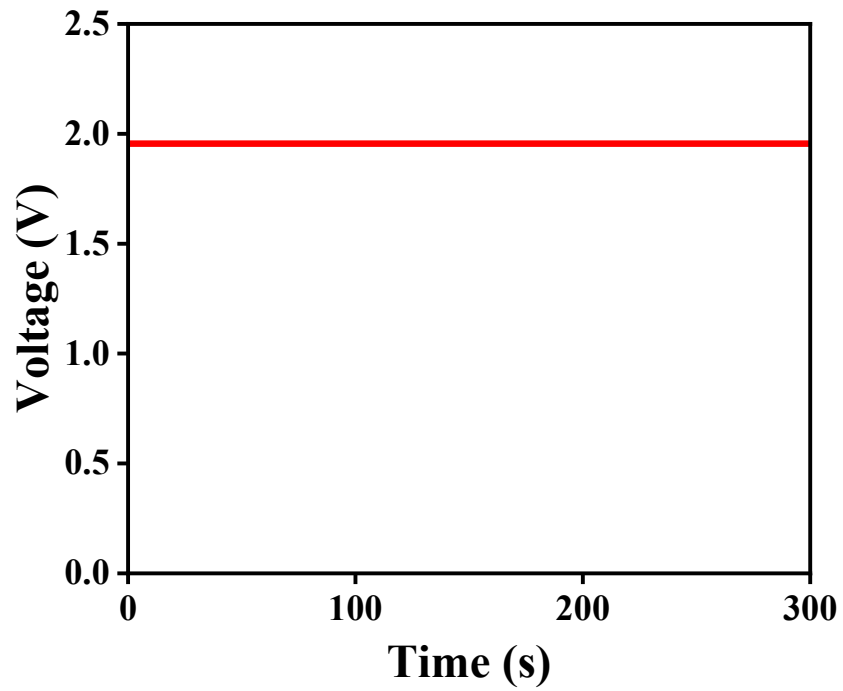


Fig. S17. Voltage output of 90 MEG units connected in parallel.

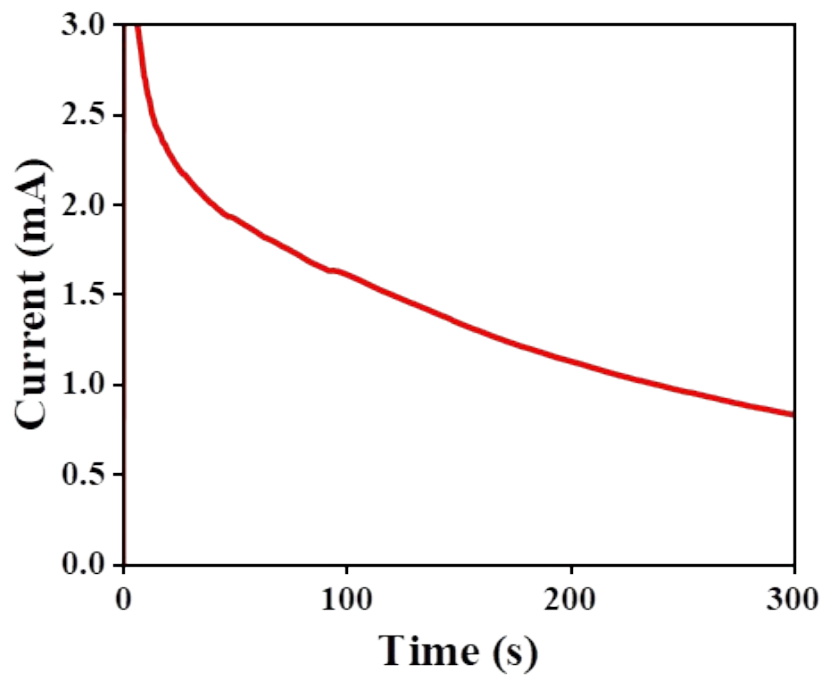
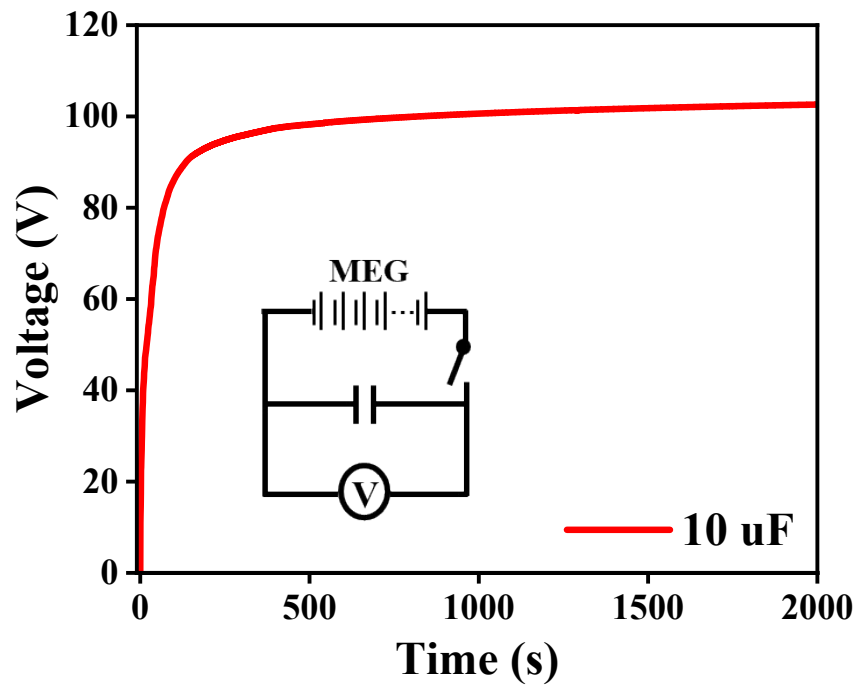
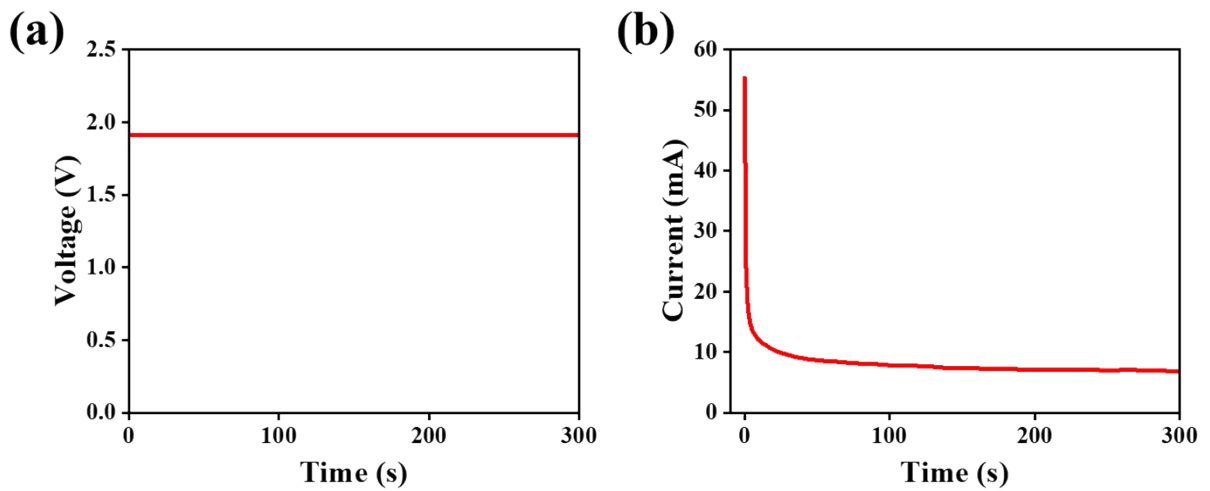


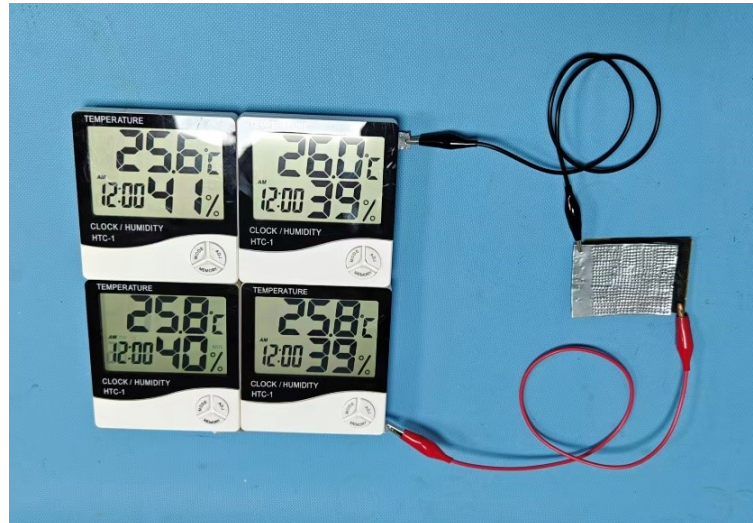
Fig. S18. Current output of 60 MEG units connected in series.



**Fig. S19.** Voltage curve of a 10  $\mu\text{F}$  commercial capacitor charged directly by 60 MEG units connected in series. The inset shows the corresponding circuit diagram.



**Fig. S20.** Output voltage (a) and current (b) of 12 MEG units connected in parallel.



**Fig. S21.** Photography of four hygro-thermographs in parallel directly powered by a single large-area CLP-MEG ( $5 \times 5 \text{ cm}^2$ ).

**Table S1.** EDS elemental composition on top surface of the CLP hydrogel after 90 days.

<b>Element</b>	<b>Line Type</b>	<b>Weight Percentage (%)</b>	<b>Wt % Sigma</b>	<b>Atomic Percentage (%)</b>
C	K series	48.47	0.73	56.97
O	K series	35.71	0.61	31.51
Cl	K series	6.81	0.13	2.71
N	K series	8.68	1.01	8.74
Zn	K series	0.34	0.13	0.07
<b>Total</b>		<b>100.00</b>		<b>100.00</b>

**Table S2.** EDS elemental composition on bottom surface of the CLP hydrogel after 90 days.

<b>Element</b>	<b>Line Type</b>	<b>Weight Percentage (%)</b>	<b>Wt % Sigma</b>	<b>Atomic Percentage (%)</b>
C	K series	47.81	0.75	56.09
O	K series	35.86	0.64	31.58
Cl	K series	6.61	0.13	2.63
N	K series	9.62	1.06	9.68
Zn	K series	0.09	0.13	0.02
<b>Total</b>		<b>100.00</b>		<b>100.00</b>